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Machine Learning in Manufacturing Technology and Systems

Guest Editor:

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Deadline for manuscript submissions:

closed (20 January 2022)

Message from the Guest Editor

Dear Colleagues,

Modern manufacturing systems are ever more developing as cyber–physical systems that are able to collect data from the surrounding physical environment and use it in order to make autonomous decisions using smart functionalities

Such systems increasingly rely on the employment of heterogeneous sensors to collect data from the manufacturing process, product, and system which can be utilized for different purposes such as the condition monitoring of machines, processes and tools; predictive maintenance; quality control; resource management; etc. To effectively take advantage of these sensors in view of realizing the smart factories of the future, artificial intelligence techniques such as machine learning can be applied.

This special issue particularly welcomes papers from all over the world on the topic of machine learning paradigms in manufacturing systems.

Prof. Dr. Doriana Marilena D'Addona Guest Editor











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Editor-in-Chief

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network

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